

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

IN RE APPLICATION OF: Young Hoon PARK, et al.

FOR: APPARATUS AND METHOD FOR DEPOSITING THIN FILM ON WAFER
USING REMOTE PLASMA

PRELIMINARY AMENDMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

Prior to the Examiner acting in the above-referenced application, please
preliminary amend the above-identified application as follows:

Amendments to the Claims are reflected in the listing of claims, which begins on page 2
of this paper.

Remarks begin on page 6 of this paper.